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Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

Claims 1-27 (Cancelled)

Claim 28 (Currently Amended) A pattern inspection apparatus comprising: an image detecting part for detecting a digital image of an object substrate; a display having a screen on which the digital image of the object substrate is and/or a distribution of defect candidates in a map form are displayable;

an input device for inputting information of a non-inspection region to be masked on the object substrate for displayby defining a region on the screen on which said distribution of defect candidates is displayed in a map form;

a memory part for storing coordinate data, pattern data or feature quantity
data of the non-inspection region to be masked on the object substrate on which a
pattern is formedinputted on the screen by the input device; and

a defect judging part in which the digital image detected by the image detecting part is examined in a state that a region matching with a condition stored in the memory part is masked and detecting a defect is detected in a region other than said masked region.

wherein an actual digital image of the detected defect is displayed together with positional information of the detected defect in a map form on the screen of the display.

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Claim 29 (Currently Amended) A pattern inspection apparatus comprising:
image detecting means for obtaining a digital image of an object substrate on
which a pattern is formed through microscopic observation thereof;

a display having a screen on which the digital image of the object substrate is displayable;

an input device for inputting information of a pre-registered region or preregistered pattern to be masked on the object substrate; for display on the screen;

defect detecting means for detecting defects of the pattern formed on said object substrate by comparing the digital image attained by the image detecting means with a reference image; and while masking the pre-registered region or a pattern matching with the pre-registered pattern; and

output means for outputting data regarding the defects detected by the defect detecting means including digital images of said defects detected by masking and the positional distribution data thereof in a map forma region matching with the information inputted by the input device.

wherein an actual digital image of the detected defect is displayed together with positional information of the detected defect in a map form on the screen of the display.

Claim 30 (Currently Amended) A pattern inspection apparatus as claimed in Claim 29,

wherein the pre-registered region or pre-registered pattern is set up using the digital image obtained by the image detecting means through microscopic observation of the object substrate by the input device.

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Claim 31-38 (Cancelled)

Claim 39 (New) A pattern inspection apparatus as claimed in Claim 28, wherein said image detecting part includes an electron beam generator which emits an electron beam and a detector which detects a secondary electron emanated from said object substrate by the irradiation of said electron beam, to detect the image of said object substrate.

Claim 40 (New) A pattern Inspection apparatus as claimed in Claim 28, wherein said image detecting part includes a light source which illuminates said object substrate with light, and a detector which detects light from the object substrate illuminated by said light source, to detect the image of said object substrate.

Claim 41 (New) A pattern inspection apparatus as claimed in Claim 29, wherein said image detecting part includes an electron beam generator which emits an electron beam and a detector which detects a secondary electron emanated from said object substrate by the irradiation of said electron beam to detect the image of said object substrate.

Claim 42 (New) A pattern Inspection apparatus as claimed in Claim 29, wherein said image detecting part includes a light source which illuminates said object substrate with light, and a detector which detects light from the object substrate illuminated by said light source, to detect the image of said object substrate.

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Claim 43 (New) A pattern inspection apparatus as claimed in claim 28, wherein the inputting is effected by a human user manually designating the non-inspection region on the display screen.

Claim 44 (New) A pattern inspection apparatus as claimed in claim 29, wherein the inputting is effected by a human user manually designating the region to be masked, on the display screen.